

AMENDMENT UNDER 37 C.F.R. § 1.116
EXPEDITING PROCEDURE
EXAMINING GROUP 1700

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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| Applicant: | Luetzen, <i>et al.</i> | Docket No.: | INF 2004 SP 00115 US |
| Serial No.: | 10/721,225 | Art Unit: | 1792 |
| Filed: | November 26, 2003 | Examiner: | George A. Goudreau |
| | | Conf. No.: | 5694 |
| For: | Method and Structures for Increasing the Structure Density and the Storage Capacitance in a Semiconductor Wafer | | |

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT UNDER 37 CFR § 1.116

Dear Sir:

Applicant respectfully submits the following amendments and remarks in response to Examiner's Office Action dated April 29, 2008, which Action is made final. Applicant respectfully requests that these amendments and remarks be entered in pursuant to the provisions of 37 CFR § 1.116, and respectfully request reconsideration of the claims.